**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**LISTING OF CLAIMS:**

1. (Currently Amended) A micro-electromechanical system, comprising a substrate ~~(S)~~ as well as a first micro-element ~~(1)~~ and a second micro-element ~~(2)~~, wherein

(a) the first micro-element ~~(1)~~ and the second micro-element ~~(2)~~ are connected to the substrate ~~(S)~~ and

(b) the first micro-element ~~(1)~~ has a first face ~~(3a)~~ and the second micro-element ~~(2)~~ has a second face ~~(4a)~~, which faces ~~(3a, 4a)~~ face one another and are produced by a structuring method,

~~characterised in~~ wherein

(d) ~~that~~ the first micro-element ~~(1)~~ contains a switch section ~~(5)~~ by which it is bistably switchable between an initial position ~~(A)~~ and a working position ~~(B)~~, and

(e) ~~that~~ the distance between the first face ~~(3a)~~ and the second surface ~~(4a)~~ in the working position ~~(B)~~ of the first micro-element ~~(1)~~ is smaller than a minimal distance producible by the structuring method between the first face ~~(3a)~~ and the second face ~~(4a)~~.

2. (Currently Amended) The micro-electromechanical system according to claim 1, ~~characterised in~~ wherein

(a) ~~that~~ the first micro-element ~~(1)~~ has a first surface ~~(3)~~ which is the same as the first face ~~(3a)~~ or, if the first face ~~(3a)~~ is provided with a first coating ~~(3b)~~, is the same as the surface of this coating ~~(3b)~~ and

(b) ~~that~~ the second micro-element ~~(2)~~ has a second surface ~~(4)~~ which is the same as the second face ~~(4a)~~ or, if the second face ~~(4a)~~ is provided with a second coating ~~(4b)~~, is the same as the surface of this coating ~~(4b)~~.

3. (Currently Amended) The micro-electromechanical system according to claim 2, wherein

(a) the second micro-element ~~(2)~~ has a first fixed end ~~(10)~~ fixedly connected to the substrate ~~(S)~~ and a movable part ~~(11)~~,

~~characterised in~~ wherein

(b) ~~that~~ the first surface ~~(3)~~ and the second surface ~~(4)~~ are electrically non-conducting and

(c) ~~that~~ the first surface ~~(3)~~ and the second surface ~~(4)~~ have contact points in the working position ~~(B)~~ and

(d) ~~that~~ the second micro-element ~~(2)~~ is thereby switchable from a switch-off position ~~(A')~~ to a switch-on position ~~(B')~~, that in the working position ~~(B)~~ of the first micro-element ~~(1)~~ the

movable part ~~(11)~~ of the second micro-element ~~(2)~~ is movable by electrostatic forces between the first micro-element ~~(1)~~ and the second micro-element ~~(2)~~.

4. (Currently Amended) The micro-electromechanical system according to claim 3, ~~characterised in~~ wherein

(a) ~~that~~ the first micro-element ~~(1)~~ comprises an electrode ~~(9)~~, which electrode ~~(9)~~ contains the first surface ~~(3)~~ and

(b) ~~that~~ the electrode ~~(9)~~ and the second micro-element ~~(2)~~ are constructed such that in the switch-on position ~~(B')~~ of the second micro-element ~~(2)~~ the first surface ~~(3)~~ and the second surface ~~(4)~~ are in full-area contact.

5. (Currently Amended) The micro-electromechanical system according to claim 4, ~~characterised in that~~ wherein the electrode ~~(9)~~ has a gap-forming surface ~~(12)~~ which is constructed such that it is set back in a step fashion with respect to the first surface ~~(3)~~ and with the second micro-element ~~(2)~~ encloses a gap ~~(13)~~ when the first micro-element ~~(1)~~ is in the working position ~~(B)~~ and the second micro-element ~~(2)~~ is in the switch-on position ~~(B')~~.

6. (Currently Amended) The micro-electromechanical system according to ~~any one of claims 3 to 5, characterised in that~~ claim 3, wherein the movable part ~~(11)~~ of the second micro-element ~~(2)~~ has a first region ~~(14)~~ and a second region ~~(15)~~, wherein the first region ~~(14)~~

- is arranged between the second region ~~(15)~~ and the first fixed end ~~(10)~~ of the second micro-element ~~(2)~~,

- comprises a part of the second surface ~~(4)~~ and

- is constructed as less stiff than the second region ~~(15)~~.

7. (Currently Amended) The micro-electromechanical system according to ~~any one of claims 3 to 5, characterised in~~ claim 3, wherein

(a) ~~that~~ the micro-electromechanical system has two fixed contacts ~~(17, 18)~~ fixedly connected to the substrate, and

(b) ~~that~~ the movable part ~~(11)~~ of the second micro-element ~~(2)~~ has an electrically conductive contact region ~~(16)~~,

- which contact region ~~(16)~~ is arranged in the area of the end of the second micro-element ~~(2)~~ opposite to the first fixed end ~~(10)~~ of the second micro-element, and

- through which contact region ~~(16)~~ in the switch-on position ~~(B')~~ of the second micro-element ~~(2)~~ the two fixed contacts ~~(17, 18)~~ are interconnected in a conducting fashion.

8. (Currently Amended) The micro-electromechanical system according to claim 7, ~~characterised in~~ wherein

(a) ~~that~~ the micro-electromechanical system comprises a third micro-element ~~(1')~~

- which is bistably switchable,

- which is connected to the substrate ~~(S)~~ and

- which is arranged in a region which lies on the side of the second micro-element ~~(2)~~ facing away from the first micro-element ~~(1)~~ and

(b) that the micro-electromechanical system has two further fixed contacts ~~(17', 18')~~ which further fixed contacts ~~(17', 18')~~ are fixedly connected to the substrate and are arranged in a region which lies on the side of the second microelement ~~(2)~~ facing away from the fixed contacts ~~(17, 18)~~,

(c) that the movable part ~~(11)~~ of the second micro-element ~~(2)~~ has a further electrically conductive contact region ~~(12')~~ which is arranged in the area of an end of the second micro-element ~~(2)~~ opposite to the first fixed end ~~(10)~~ of the second micro-element ~~(2)~~, on the side of the second micro-element ~~(2)~~ facing away from the contact region ~~(16)~~, and

(d) wherein the third micro-element ~~(1')~~ interacts with the second micro-element ~~(2)~~ and with the further fixed contacts ~~(17', 18')~~ in a fashion similar to that in which the first micro-element ~~(1)~~ interacts with the second micro-element ~~(2)~~ and with the fixed contacts ~~(17, 18)~~.

9. (Currently Amended) The micro-electromechanical system according to claim 6 ~~and claim 7 or according to claim 6 and claim 8, characterised in~~ wherein

~~that~~ the contact region ~~(16)~~ is arranged in the second region ~~(15)~~ of the movable part ~~(11)~~ of the second micro-element ~~(2)~~.

10. (Currently Amended) The micro-electromechanical system according to claim 1, ~~characterised in~~ wherein

(a) ~~that~~ the micro-electromechanical system comprises a third micro-element ~~(1')~~ which

- is connected to the substrate ~~(S)~~ and

- has a third face ~~(3a')~~,

(b) ~~that~~ the second micro-element ~~(2)~~ contains a switch section which has

- a first fixed end ~~(10)~~ fixedly connected to the substrate ~~(S)~~,

- a second fixed end ~~(10')~~ fixedly connected to the substrate ~~(S)~~,

- a movable part ~~(11)~~ arranged between these two fixed ends ~~(10, 10')~~ and
- a fourth face ~~(4a')~~

and

(c) through which switch section the second micro-element ~~(2)~~ is switchable between a switch-off position ~~(A')~~ and a switch-on position ~~(B')~~,

wherein

(d) the movable part ~~(11)~~ of the second micro-element ~~(2)~~ comprises an electrically conductive contact region ~~(16)~~,

(e) the second face ~~(4a)~~ is arranged between the first fixed end ~~(10)~~ and the contact region ~~(16)~~, and

(f) the fourth face ~~(4a')~~ is arranged between the second fixed end ~~(10')~~ and the contact region ~~(16)~~,

(g) the third face ~~(3a')~~ and the fourth face ~~(4a')~~ are produced by the structuring method and are facing one another, and

(h) ~~that~~ the third micro-element ~~(1')~~ contains a switch section through which it is bistably switchable between an initial position ~~(A)~~ and a working position ~~(B)~~, and

(i) ~~that~~ the distance between the third surface ~~(3a')~~ and the fourth face ~~(4a')~~ in the working position ~~(B)~~ of the third micro-element ~~(1')~~ is smaller than a minimal distance producible by the structuring method between the third face ~~(3a')~~ and the fourth face ~~(4a')~~.

11. (Currently Amended) The micro-electromechanical system according to claim 10, ~~characterised in~~ wherein

(a) ~~that~~ the third micro-element ~~(1')~~ has a third surface ~~(3')~~ which is the same as the third face ~~(3a')~~ or, if the third face ~~(3a')~~ is provided with a third coating ~~(3b')~~, is the same as the surface of this coating ~~(3b')~~, and

(b) ~~that~~ the second micro-element ~~(2)~~ has a fourth face ~~(4')~~ which is the same as the fourth face ~~(4a')~~ or, if the fourth face ~~(4a')~~ is provided with a fourth coating ~~(4b')~~, is the same as the surface of this coating ~~(4b')~~.

12. The micro-electromechanical system according to claim 11, ~~characterised in~~ wherein

(a) ~~that~~ the micro-electromechanical system contains two fixed contacts ~~(17, 18)~~ fixedly connected to the substrate ~~(S)~~,

(b) ~~that~~ the second micro-element ~~(2)~~ is thereby switchable from its initial position ~~(A')~~ into its switch-on position ~~(B')~~, that in the working position ~~(B)~~ of the first micro-element ~~(1)~~ and of the third micro-element ~~(1')~~ the movable part ~~(11)~~ of the second micro-element ~~(2)~~ is elastically movable by electrostatic forces between the first microelement ~~(1)~~ and the second micro-element ~~(2)~~ and between the third micro-element ~~(1')~~ and the second micro-element ~~(2)~~, and

(c) ~~that~~ in the switch-on position ~~(B')~~ of the second micro-element ~~(2)~~ the two fixed contacts ~~(17, 18)~~ are interconnected by the contact region ~~(16)~~ in a conducting fashion.

13. (Currently Amended) The micro-electromechanical system according to claim 12, ~~characterised in~~ wherein

(a) ~~that~~ the micro-electromechanical system comprises

- a fourth micro-element ~~(19)~~ and

- a fifth micro-element ~~(20)~~

(b) which micro-elements ~~(19, 20)~~

- are connected to the substrate ~~(S)~~ in an area which lies on the side of the second micro-element ~~(2)~~ facing away from the fixed contacts ~~(17, 18)~~,
- contains switch sections through which they are bistably switchable between an initial position ~~(A)~~ and a working position ~~(B)~~, and

- which each have a contact electrode ~~(21, 22)~~ provided with an electrically conductive coating, and

(c) ~~that in~~ the switch-off position ~~(A')~~ of the second micro-element ~~(2)~~ in the working position ~~(B)~~ of the fourth microelement ~~(19)~~ and the fifth micro-element ~~(20)~~ the two contact electrodes ~~(21, 22)~~ are interconnected by the contact region ~~(16)~~ in an electrically conducting fashion.

14. (Currently Amended) The micro-electromechanical system according to ~~any one of claims 10 to 13, characterised in that~~ claim 10, wherein the second micro-element ~~(2)~~ is bistably elastically switchable between its initial position ~~(A')~~ and its switch-on position ~~(B')~~.

15. (Currently Amended) The micro-electromechanical system according to claim 14, ~~characterised in~~ wherein

(a) ~~that~~ the micro-electromechanical system comprises

- a sixth micro-element ~~(23)~~ and

- a seventh micro-element ~~(24)~~,

(b) which micro-elements ~~(23, 24)~~

- are connected to the substrate ~~(S)~~,

- are arranged on the side of the second micro-element ~~(2)~~ which is facing away from the second surface ~~(4)~~ and the fourth surface ~~(4')~~,

- contain switch sections through which they are bistably switchable between an initial position (A) and a working position ~~(B)~~,

(c) ~~that~~ the sixth micro-element ~~(23)~~ has a fifth face ~~(25a)~~,

(d) ~~that~~ the second micro-element ~~(2)~~ has a sixth face ~~(26a)~~ which is arranged on the side of the second micro-element ~~(2)~~ facing away from the second surface ~~(4)~~ between the first fixed end ~~(10)~~ and the contact region ~~(16)~~,

(e) ~~wherein~~ the fifth face ~~(25a)~~ and the sixth face ~~(26a)~~ are facing one another and are produced by the structuring method,

(f) ~~that~~ the seventh micro-element ~~(24)~~ has a seventh face ~~(25a')~~,

(g) ~~that~~ the second micro-element ~~(2)~~ has an eighth face ~~(26a')~~ which is arranged on the side of the second micro-element ~~(2)~~ facing away from the fourth surface ~~(4')~~ between the second fixed end ~~(10')~~ and the contact region ~~(16)~~,

(h) ~~wherein~~ the seventh face ~~(25a')~~ and the eighth face ~~(26a')~~ are facing one another and produced by the structuring method, and

(i) ~~that~~ the distance between the fifth face ~~(25a)~~ and the sixth face ~~(26a)~~ in the working position ~~(B)~~ of the sixth micro-element ~~(23)~~ is smaller than a minimal distance producible by the structuring method between the fifth face ~~(25a)~~ and the sixth face ~~(26a)~~, and

(i) ~~that~~ the distance between the seventh face ~~(25a')~~ and the eighth face ~~(26a')~~ in the working position ~~(B)~~ of the seventh micro-element ~~(24)~~ is smaller than a minimal distance

producible by the structuring method between the seventh face ~~(25a')~~ and the eighth face ~~(25a', 26a')~~ and

(j) ~~that~~ the second micro-element ~~(2)~~ is thereby switchable from its switch-on position ~~(B')~~ into its switch-off position ~~(A')~~, that in the working position ~~(B)~~ of the sixth micro-element ~~(23)~~ and the seventh micro-element ~~(24)~~ the movable part ~~(11)~~ of the second micro-element ~~(2)~~ is elastically movable by electrostatic forces between the sixth micro-element ~~(23)~~ and the second micro-element ~~(2)~~ and between the seventh micro-element ~~(24)~~ and the second micro-element ~~(2)~~.

16. (Currently Amended) The micro-electromechanical system according to ~~any one of claims 14 or 15~~ claim 14, wherein

(a) the substrate ~~(S)~~ is constructed as a flat extensive solid with a principal surface, and

(b) the micro-elements ~~(1, 1', 2, 19, 20, 23, 24)~~ are constructed as regular prismatic bodies whose base surfaces are aligned parallel to the principal surface, ~~characterised in~~ wherein

(c) ~~that~~ the movable part of the second micro-element ~~(2)~~

- is constructed as a regular prismatic body and

- is laterally movable and

(d) ~~that~~ the base surface of the regular prismatic body forming the movable part ~~(11)~~

either

- has the form of a symmetrical antinode in the switch-off position ~~(A')~~ and

- has the form of an asymmetric antinode in the switch-on position ~~(B')~~,

or

- describes two parallel cosinusoidal lines which are interconnected at the centre ~~(8)~~ between their two ends ~~(6, 7)~~.

17. (Currently Amended) The micro-electromechanical system according to ~~any one of claims 1 to 16~~ claim 1, wherein

(a) the substrate ~~(S)~~ is constructed as a flat extensive body with a principal surface and

(b) ~~the micro-elements~~ each micro-element is ~~(1, 1', 2, 19, 20, 23, 24) are~~ constructed as regular prismatic bodies whose base surfaces are aligned parallel to the principal surface, ~~characterised in~~ wherein

(c) ~~that~~ there is at least one micro-element ~~(1, 1', 2, 19, 20, 23, 24)~~ bistably switchable between an initial position ~~(A)~~ and a working position ~~(B)~~, whose switch section contains

- a first fixed end fixedly connected to the substrate ~~(S)~~,

- a second fixed end fixedly connected to the substrate ~~(S)~~ and

- a movable part arranged between these two fixed ends,

(d) which movable part

- is constructed as a regular prismatic body and

- is laterally movable and

(e) ~~that~~ the base surface of the regular prismatic body forming the movable part

either

- has the form of a symmetrical antinode in the switch-off position ~~(A')~~ and

- has the form of an asymmetric antinode in the switch-on position ~~(B')~~,

or

- describes two parallel cosinusoidal lines which are interconnected at the centre ~~(8)~~ between their two ends.

18. (Currently Amended) The micro-electromechanical system according to claim 3, ~~characterised in that~~ wherein

the movable part ~~(11)~~ of the second micro-element ~~(2)~~ is elastically deformable from the initial position A to the working position A by switching the first micro-element ~~(1)~~.

19. (Currently Amended) The micro-electromechanical system according to claim 18, ~~characterised in~~ wherein

(a) ~~that~~ the micro-electromechanical system has two fixed contacts ~~(17, 18)~~ fixedly connected to the substrate and

(b) that the movable part ~~(11)~~ of the second micro-element ~~(2)~~ has an electrically conductive contact region ~~(16)~~,

- which contact region ~~(16)~~ is arranged in the area of an end of the second micro-element ~~(2)~~ opposite to the first fixed end ~~(10)~~ of the second micro-element ~~(2)~~ and

- through which contact region ~~(16)~~ in the switch-off position ~~(A')~~ of the second-microelement ~~(2)~~ the two fixed contacts ~~(17, 18)~~ are interconnected in a conducting fashion.

20. (Currently Amended) The micro-electromechanical system according to ~~any one of claims 1 to 9 or 18 or 19~~ claim 1, wherein

(a) the substrate ~~(S)~~ is constructed as a flat extensive body with a principal surface, characterised in

(b) ~~that~~ the switch section ~~(5)~~ of the first micro-element ~~(1)~~ is horizontally movable and

(c) ~~that~~ the movable part ~~(11)~~ of the second micro-element ~~(2)~~ is horizontally movable.

21. (Currently Amended) A method for manufacturing a micro-electromechanical system in which method

(a) a first micro-element ~~(1)~~ connected to the substrate is produced from a substrate ~~(S)~~ and

(b) a second micro-element ~~(2)~~ connected to the substrate is produced from a substrate, and

(c) using a structuring method, a first face ~~(3a)~~ of the first micro-element ~~(1)~~ and a second face ~~(4a)~~ of the second micro-element ~~(2)~~ are formed which faces ~~(3a, 4a)~~ face one another and are at a distance from one another,

~~characterised in~~ wherein

(d) ~~that~~ the first micro-element ~~(1)~~ is formed such that

- it is located in an initial position ~~(A)~~,

- it is bistably switchable from the initial position ~~(A)~~ into a working position ~~(B)~~ and

- the distance of the first face ~~(3a)~~ from the second face ~~(4a)~~ in the working position ~~(B)~~ is smaller that a minimal distance producible by the structuring method between the first face ~~(3a)~~ and the second face ~~(4a)~~ and

(e) ~~that~~ after forming the first face ~~(3a)~~ and the second face ~~(4a)~~ by the structuring method, the first micro-element ~~(1)~~ is switched into the working position ~~(B)~~.

22. (Currently Amended) The method of manufacture according to claim 21, ~~characterised in that~~ wherein before switching the first micro-element ~~(1)~~ into the working position ~~(B)~~, the first face ~~(3a)~~ of the first micro-element ~~(1)~~ is provided with a first electrically conducting or electrically non-conducting coating ~~(3b)~~,

and/or

the second face ~~(4a)~~ of the second micro-element ~~(2)~~ is provided with a second electrically conducting or electrically non-conducting coating ~~(4b)~~.

23. (Currently Amended) The method of manufacture according to claim 21, wherein ~~any one of claims 21 to 22, characterised in that one of the electro-mechanical systems is manufactured according to any one of claims 1 to 20.~~ a resulting micro-electro mechanism system comprises a substrate as well as a first micro-element and a second micro-element, wherein

(a) the first micro-element and the second micro-element are connected to the substrate and

(b) the first micro-element has a first face and the second micro-element has a second face, which faces face one another and are produced by a structuring method,

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wherein

(d) the first micro-element contains a switch section by which it is bistably switchable between an initial position and a working position, and

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(e) the distance between the first face and the second surface in the working position of the first micro-element is smaller than a minimal distance producible by the structuring method between the first face and the second face.